

03560.002760

PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:)	
Shuichi YABU	:	Examiner: A. Mathews
)	
Application No.: 09/811,447	:	Group Art Unit: 2851
)	
Filed: March 20, 2001	:	
)	
For: EXPOSURE APPARATUS, GAS REPLACING	:	
METHOD, AND METHOD OF	:	
MANUFACTURING A SEMICONDUCTOR	:	
DEVICE	:	June 24, 2003

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

INFORMATION DISCLOSURE STATEMENT

Sir:

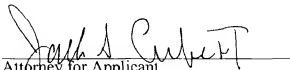
In compliance with the duty of disclosure under 37 C.F.R. § 1.56 and in accordance with the practice under 37 C.F.R. §§ 1.97 and 1.98, the Examiner's attention is directed to the documents listed on the enclosed PTO-1449 form. Copies of the listed documents are also enclosed.

Applicants request that the above information be considered by the Examiner and that a copy of the enclosed PTO-1449 form be initialed and returned indicating that such information has been considered.

This Information Disclosure Statement is being filed before issuance of an Office Action on the merits. Therefore, no fee under 37 C.F.R. 1.97(c)(2) is believed due. Nevertheless, the Commissioner may charge Deposit Account No. 06-1205, should any fee be due for filing this paper.

Applicant's undersigned attorney may be reached in our Washington D.C. office by telephone at (202) 530-1010. All correspondence should continue to be directed to our address given below.

Respectfully submitted,



Attorney for Applicant
Jack S. Cubert
Registration No. 24,245

FITZPATRICK, CELLA, HARPER & SCINTO
30 Rockefeller Plaza
New York, New York 10112-3801
Facsimile: (212) 218-2200

SEW/JSC/dc

